AMENDMENTS TO THE CLAIMS

The following Listing of Claims replaces all prior versions, and listings, of claims in the present application.

Listing of Claims

1-10. (Canceled).

11. (Previously presented) A method of forming a nozzle plate for droplet deposition apparatus, including the steps of:

defining a plurality of distinct bodies of polymeric material distributed over a nozzle plane, each said body having a periphery,

forming a plurality of nozzles, each nozzle extending through one of said distinct bodies of polymeric material distributed over the nozzle plate plane,

and subsequently to said step of defining a plurality of distinct bodies of polymeric material, forming at least one metal nozzle plate layer by electroforming around said peripheries of said bodies of polymeric material so that each of said distinct bodies of polymeric material is located within a corresponding one of a plurality of apertures within said metal nozzle plate layer and so that said peripheries of said bodies of polymeric material define at least in part the shapes of said apertures;

to provide a nozzle plate extending over said nozzle plate plane.

12-17 (Canceled).

18. (Previously presented). A method of forming a nozzle plate component for a droplet deposition apparatus, said method comprising the steps of:

forming a layer of first photoresist material on a substrate;

subsequently selectively exposing and removing some of said first photoresist material to define on the substrate an array of distinct bodies of said first photoresist material;

Application No. 10/564,969 Docket No.: 27754/26717

Amendment dated July 13, 2011

After Allowance Under 37 C.F.R. 1.312

subsequent to said step of selectively exposing and removing first photoresist material,

forming a first plate of metal around said distinct bodies of said first photoresist material, so as

to form a metal nozzle plate having an array of apertures corresponding to said array of distinct

bodies of said first photoresist material, each aperture containing one of said bodies of said first

photoresist material; and

forming a nozzle extending through each of said distinct bodies_of said first photoresist

material.

19. (Original). A method according to Claim 18, further comprising the step of depositing a

metallic layer on the substrate prior to forming of the layer of first photoresist material, said

first plate of metal being electroformed with said metallic layer serving as a seed layer.

20-21 (Canceled).

22. (Previously presented). A method according to claim 11, wherein each of said nozzles is

formed by ablating each of said nozzles through one of said distinct bodies of polymeric

material located within a corresponding one of a plurality of apertures within said metal nozzle

plate layer.

23. (Previously presented). A method according to claim 18, wherein each of said nozzles is

formed by ablating each of said nozzles through one of said distinct bodies of said first

photoresist material contained within an aperture in said first plate of metal.

24. (Previously presented) A method according to claim 11, further comprising the step of

forming a further layer in addition to said metal nozzle plate layer, said further layer comprising

a plurality of apertures aligned with said nozzles.

3

Application No. 10/564,969 Docket No.: 27754/26717

Amendment dated July 13, 2011 After Allowance Under 37 C.F.R. 1.312

25. (Previously presented) A method according to claim 18, wherein each of said nozzles has a

diameter and wherein said step of selectively exposing and removing said first photoresist

material to define on the substrate an array of distinct bodies of said first photoresist material

comprises applying a mask, said mask comprising an array of distinct mask features

corresponding to said array of distinct bodies, each of said mask features having a diameter

greater than the diameter of the nozzle of the corresponding body of first photoresist material.

26. (Previously presented) A method according to claim 18, further comprising the step of

forming a further layer in addition to said metal nozzle plate layer, said further layer comprising

a plurality of apertures aligned with said nozzles.

27. (New) A method according to Claim 11, wherein the nozzle plate comprises a first nozzle

plate layer containing said apertures and the polymeric material located within said apertures

through which the nozzles extend, and a second nozzle plate layer comprising a guard layer.

28. (New) A method according to Claim 27, wherein said guard layer comprises, for each

nozzle, a guard aperture which is a dimension in the nozzle plane larger than that of the

nozzle and smaller than that of the polymeric material through which the nozzle extends.

29. (New) A method according to Claim 27, wherein said second nozzle plate layer is formed

by the steps of defining a plurality of distinct bodies of guard layer polymeric material

distributed over the first nozzle plate layer, forming said guard layer by electroforming

around said bodies of polymeric material and removing said guard layer polymeric material.

30. (New) A method according to Claim 29, wherein said guard layer polymeric material is

removed prior to formation of nozzles.

4

Application No. 10/564,969 Docket No.: 27754/26717

Amendment dated July 13, 2011 After Allowance Under 37 C.F.R. 1.312

31. (New) A method according to Claim 29, wherein nozzles are formed by ablation prior to

removal of said guard layer polymeric material.

32. (New) A method according to Claim 11, wherein the nozzle plate comprises a first nozzle

plate layer containing said apertures and the polymeric material located within said apertures

through which the nozzles extend, and a second nozzle plate layer comprising a connecting

tracks layer.

33. (New) A method according to Claim 18, further comprising the steps of:

forming a layer of second photoresist material on the first plate of metal;

selectively exposing and removing some of said second photoresist material to define

an array of distinct bodies of said second photoresist material aligned respectively with the

bodies of said first photoresist material;

forming a second plate of metal around said bodies of second material; and

removing said second photoresist material to form apertures in the guard plate

respectively aligned with the nozzles.

5